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*Hoover, A.; Jean-Baptiste, G.; Jiang, X.; Flynn, P.J.; Bunke, H.; Goldgof, D.B. Bowyer, K.; Eggert, D.W.; Fitzgibbon, A.; Fisher, R.B.;*  
*Pattern Analysis and Machine Intelligence, IEEE Transactions on*, Volume: 18 , Issue: 7 , July 1996  
 Pages:673 - 689

[\[Abstract\]](#) [\[PDF Full-Text \(2068 KB\)\]](#) **IEEE JNL****2 Modeling and calibration of a structured light scanner for 3-D robot vision**

*Chen, C.; Kak, A.;*  
*Robotics and Automation. Proceedings. 1987 IEEE International Conference on*, Volume: 4 , Mar 1987  
 Pages:807 - 815

[\[Abstract\]](#) [\[PDF Full-Text \(880 KB\)\]](#) **IEEE CNF****3 Comparing curved-surface range image segmenters**

*Powell, M.W.; Bowyer, K.W.; Xiaoyi Jiang; Bunke, H.;*  
*Computer Vision, 1998. Sixth International Conference on*, 4-7 Jan. 1998  
 Pages:286 - 291

[\[Abstract\]](#) [\[PDF Full-Text \(852 KB\)\]](#) **IEEE CNF****4 Determination of the identity, position and orientation of the topmost object in a pile: Some further experiments**

*Yang, H.; Kak, A.;*  
*Robotics and Automation. Proceedings. 1986 IEEE International Conference on*, Volume: 3 , Apr 1986

Pages:293 - 298

[\[Abstract\]](#) [\[PDF Full-Text \(552 KB\)\]](#) [IEEE CNF](#)

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**5 Automatic relighting of overlapping textures of a 3D model**

*Beauchesne, E.; Sbastien, R.;*

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Pages:II - 166-73 vol.2

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**6 Dual-beam structured-light scanning for 3-D object modeling**

*Park, J.; DeSouza, G.N.; Kak, A.C.;*

3-D Digital Imaging and Modeling, 2001. Proceedings. Third International  
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**1 Self-oscillating evanescent microwave probes for nondestructive evaluations of materials**

*Tabib-Azar, M.; Tao Zhang; LeClair, S.R.;*  
Instrumentation and Measurement, IEEE Transactions on, Volume: 51, Issue: 5, Oct. 2002  
Pages: 1126 - 1132

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**2 A new technique for automated wafer inspection and classification particles and crystalline defects**

*Lie Dou; Broderick, M.-P.;*  
Advanced Semiconductor Manufacturing Conference and Workshop, 1997. IEEE /SEMI, 10-12 Sept. 1997  
Pages: 180 - 184

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**3 Detection of urban areas in multispectral data**

*Boehmsdorff, S.; Bers, K.; Brehm, T.; Essen, H.; Jager, K.;*  
Remote Sensing and Data Fusion over Urban Areas, IEEE/ISPRS Joint Workshop 2001, 8-9 Nov. 2001  
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*Ferrara, M.B.; Welch, K.A.; Clementi, L.D.; Hunt, J.D.; Wolter, S.D.; Bates, E.*  
Advanced Semiconductor Manufacturing Conference and Workshop, 1995. AS 95 Proceedings. IEEE/SEMI 1995, 13-15 Nov. 1995

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